IN THE SPECIFICATION

Please replace the paragraph beginning at page 1, line 14 with the following replacement paragraph.

--Since the development of the scanning tunneling microscope (hereinafter represented as STM) (G. Binnig et al., Phys. Rev. Lett, 49, 57(1982)) capable of directly observing the electronic structure of surfacial atoms of a conductor has enabled the measurement of both monocrystalline and amorphous materials with a high resolution in a real spatial image, the scanning probe microscopes (SPM) are being actively investigated in the field of evaluation of microstructures of various materials. Among the SPM, there are known a scanning tunneling microscope (STM), an atomic force microscope (AFM), a magnetic force microscope (MFM) etc. which detect the surfacial structure by a tunneling current, an atomic force, a magnetic force, a light etc. obtained by positioning a probe with a micro-tip close to a specimen to be evaluated.--

Please replace the paragraph beginning at page 4, line 18 with the following replacement paragraph.

--In consideration of the foregoing, the object of the present invention is to provide a light detecting or irradiating probe capable of reducing the light transmission loss between the waveguide and the optical microaperture or that in the short wavelength region in the waveguide while maintaining the advantage of fabricating easily a plurality of the probes by easy integration and easy size reduction in the method of the aforementioned Japanese Patent Application Laid-open No. 10-293134, which probe can be fabricated by a

batch process with a high productivity and a satisfactory process reproducibility of the optical microaperture, a producing method therefor, a surface observation apparatus, an exposure apparatus and an information processing apparatus.--

Please replace the paragraph beginning at page 5, line 27 with the following replacement paragraph.

--forming a hollow tip having a microaperture on the opening, and--

Please replace the paragraph beginning at page15, line 26 with the following replacement paragraph.

--It is also possible to provide a surface observation apparatus, an exposure apparatus or a recording-reproducing apparatus of a high transfer rate by parallel processing of information utilizing a multi-probe utilizing the configuration of the present invention. The recording medium in such application can be, as an example of the recording medium showing a change in the optical characteristics by a voltage application, a diacetylene derivative polymer such as 10, 12-pentacosadiinic acid which causes a change in the structure by Joule's heat resulting from a local current generated by a voltage application thereby showing a shift in the peak wavelength of the light absorption band, as described in the Japanese Patent Application Laid-open No. 4-90152. Also as an example of the recording medium showing a change in the optical characteristics by a voltage application under light irradiation, there can be mentioned an azo compound having a quinone radical and a hydroquinone radical showing a cis-trans photomesomeric reaction